

MNC 2017 (November 6-9, Ramada Plaza JeJu Hotel, JeJu, Korea) Schedule

Monday, November 6

Room A
18:00-20:00 Welcome Reception

Tuesday, November 7

Room A			
7P-1: Opening & Plenary Session I, 9:30-12:00			
<i>Lunch</i>			
Room A	Room B	Room C	Room D
7A-2: 13:30-15:20 Nano-Scale Transistors	7B-2: 13:30-15:50 Graphene: Materials, Characterization and Applications	7C-2: 13:30-15:30 Organic Nanomaterials I	7D-2: 13:30-16:00 Nanoimprint, Nanoprint and Rising Lithography
			7D-2 Author's Interview: 16:00-16:10
<i>Coffee Break</i>			
7A-3: 15:40-17:40 Advanced Nano Memory Devices	7B-3: 16:00-18:00 2D Materials for Electronic Applications	7C-3: 15:50-17:50 Organic Nanomaterials II	7D-3: 16:20-17:50 Inorganic Materials I
7A-2, 3 Author's Interview: 17:40-17:50	7B-2, 3 Author's Interview: 18:00-18:10	7C-2, 3 Author's Interview: 17:50-18:00	7D-3 Author's Interview: 17:50-18:00

Wednesday, November 8

Room A			
8P-4: Plenary Session II, 8:30-9:10			
Room A	Room B	Room C	Room D
8A-5: 9:20-10:30 Optoelectronic Devices	8B-5: 9:20-10:50 Nanocarbon Characterization	8C-5: 9:20-10:40 Resist and Directed Self-Assembly I	8D-5: 9:20-10:50 Microsystem Technology and MEMS I
	8B-5 Author's Interview: 10:50-11:00		
<i>Lobby</i>			
<i>Coffee Break</i>			
8A-6: 10:50-12:10 Next Generation Nanodevices	8B-6: 11:10-12:20 Nanofabrication I	8C-6: 11:00-12:10 Resist and Directed Self-Assembly II	8D-6: 11:10-12:30 Microsystem Technology and MEMS II
8A-5, 6 Author's Interview: 12:10-12:20	8B-6 Author's Interview: 12:20-12:30	8C-5, 6 Author's Interview: 12:10-12:20	8D-5, 6 Author's Interview: 12:30-12:40
<i>Lunch</i>			
<i>Lobby</i>			
8P-7: 13:30-15:30 Poster Session I Electron and Ion Beam Technology, Resist and Directed Self-Assembly, Nanocarbons, Nanodevices, Nanofabrication, Organic Nanomaterials, NanoTool, Nanoimprint, Nanoprint and Rising Lithography, BioMEMS, Lab on a Chip and Microsystem Technology and MEMS			
Room A → Room B	Room B → Room C	Room C → Room D	Room D → Room E
8A-8: 15:40-17:50 2D Nanodevices	8B-8: 15:40-17:50 Nanofabrication II	8C-8: 15:40-18:00 Electron and Ion Beam Technologies	8D-8: 15:40-18:00 Nano Tool
8A-8 Author's Interview: 17:50-18:00	8B-8 Author's Interview: 17:50-18:00	8C-8 Author's Interview: 18:00-18:10	8D-8 Author's Interview: 18:00-18:10
Room A			
18:30-20:30 Banquet			

Thursday, November 9

Room A	Room B	Room C	Room D
9A-9: 9:00-10:30 Microsystem Technology and MEMS III	9B-9: 9:00-10:30 Nanofabrication III	9C-9: 9:00-10:10 Advanced Lithography I	9D-9: 9:00-10:10 Bio MEMS and Lab on a Chip I
9A-9 Author's Interview: 10:30-10:40			
<i>Lobby</i>			
<i>Coffee Break</i>			
9A-10: 10:50-12:00 Inorganic Nano Materials II	9B-10: 10:50-11:50 Nanofabrication IV	9C-10: 10:30-11:40 Advanced Lithography II	9D-10: 10:30-11:40 Bio MEMS and Lab on a Chip II
9A-10 Author's Interview: 12:00-12:10	9B-9, 10 Author's Interview: 11:50-12:00	9C-9, 10 Author's Interview: 11:40-11:50	9D-9, 10 Author's Interview: 11:40-11:50
<i>Lunch</i>			
9A-11: 13:30-15:00 Inorganic Nano Materials III	9B-11: 13:30-14:50 Nanofabrication V	9C-11: 13:30-14:40 Advanced Lithography III	9D-11: 13:30-14:30 Bio MEMS and Lab on a Chip III
9A-11 Author's Interview: 15:00-15:10	9B-11 Author's Interview: 14:50-15:00	9C-11 Author's Interview: 14:40-14:50	9D-11 Author's Interview: 14:30-14:40
<i>Lobby</i>			
9P-12: 15:20-17:20 Poster Session II Advanced Photolithography, Nanocarbons, Nanodevices, Nanofabrication and Inorganic Nanomaterials			